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TITLE OF THE INVENTION

SUBSTRATE FOR MAGNETIC RECORDING MEDIA, MAGNETIC
RECORDING MEDIA AND MAGNETIC RECORDING APPARATUS

BACKGROUND OF THE INVENTION

5 The present invention relates to a substrate for
a magnetic recording media having protrusions and
recesses formed thereon, a magnetic recording media of
substrate processing type and a magnetic recording
apparatus having the magnetic recording media mounted
10 thereto.

 In increasing the track density of a hard disc
drive (HDD), interference between the adjacent tracks
has come to be a problem to be solved. In particular,
how to lower fringing caused by the fringe effect of a
15 magnetic field from the write head is a serious
technical problem to be solved. A discrete track type
patterned media (DTR media) in which recording tracks
are physically separated makes it possible to suppress
a side erase phenomenon in recording and a side read
20 phenomenon in reproducing so as to increase markedly
the density in the cross-track direction and, thus, is
expected to provide a magnetic recording media capable
of high density recording.

 The DTR media includes a magnetic film etching
25 type and a substrate processing type. A large number
of manufacturing steps are required for obtaining the
DTR media of the magnetic film etching type, leading

to a high manufacturing cost. Therefore, the substrate processing type DTR media, prepared by first producing a substrate having protrusions and recesses and then depositing a magnetic film by sputtering, is
5 suitable to mass production of the DTR media.

In the substrate processing type DTR media, however, the magnetic film is also formed on the recesses, with the result that the signal-to-noise ratio (SNR) is lowered by magnetic signals from the
10 recesses. Under the circumstances, it is considered effective to lower the magnetic characteristics of the magnetic film present on the recesses.

A method of manufacturing a patterned media is proposed in, for example, Japanese Patent Disclosure
15 (Kokai) No. 2002-359138. It is disclosed in this prior art that the surface of a ferromagnetic layer is selectively covered with a mask so as to permit the surface of the ferromagnetic layer to be selectively exposed to a reactive gas containing a halogen
20 element, thereby denaturing the exposed portions. Also, a method of manufacturing a patterned media by selectively oxidizing the masked surface of the media is disclosed in U.S. Patent No. 6,168,845. Further, proposed in Japanese Patent Disclosure No. 5-205257 is
25 a method that ions such as nitrogen ions or oxygen ions are introduced into those regions of the magnetic layer positioned between the recording tracks of the

discrete track media so as to make the magnetic layer on those regions nonmagnetic. However, it is difficult to carry out these methods.

Also proposed is a patterned media prepared by forming a multilayered Co/Pt magnetic layer on a Si substrate having protrusions and recesses; see Phys. Rev. B 62, 12271-12281 (2000). The magnetic characteristics of the Co/Pt multilayered film are highly sensitive to the multilayered structure. Specifically, a clear multilayered structure can be obtained on the protrusions and the multilayered structure is disturbed on the recesses, making it possible to form patterns. However, the particular method cannot be applied to a granular type perpendicular magnetic film.

BRIEF SUMMARY OF THE INVENTION

According to one aspect of the present invention, there is provided a substrate for a magnetic recording media, comprising: circumferential protrusions corresponding to recording tracks and circumferential recesses corresponding to grooves between the recording tracks; the substrate satisfying at least one of conditions (a) to (f) given below: (a) a surface of the recess has a surface energy smaller than that of a surface of the protrusion; (b) the surface of the recess is modified with a thermally decomposable or thermally deformable substance; (c)

the surface of the recess has surface roughness smaller than that of the surface of the protrusion; (d) crystal orientation is more disturbed on the surface of the recess than on the surface of the protrusion; (e) the surface of the recess is modified with a substance that causes reaction with a magnetic material or that diffuses into the magnetic material; and (f) the surface of the recess is modified with a substance soluble in a solvent or with a deformable substance.

According to another aspect of the present invention, there is provided a magnetic recording media, comprising: the above substrate for a magnetic recording media; and a granular magnetic layer formed on the substrate for the magnetic recording media, the orientation of the magnetic crystal lattice of the magnetic layer on the recess being more disturbed than that of the magnetic layer on the protrusion.

BRIEF DESCRIPTION OF THE SEVERAL VIEWS OF THE DRAWING

FIG. 1 is a cross-sectional view showing a substrate for a magnetic recording media (HDD substrate) according to an embodiment of the present invention;

FIG. 2 is a cross-sectional view showing a magnetic recording media (DTR media) according to an embodiment of the present invention;

FIGS. 3A, 3B, 3C, 3D, 3E and 3F are

cross-sectional views showing a method of manufacturing the HDD substrate shown in FIG. 1 and the DTR media shown in FIG. 2;

FIG. 4 is a cross-sectional view showing a substrate for a magnetic recording media (HDD substrate) according to another embodiment of the present invention;

FIG. 5 is a cross-sectional view showing a magnetic recording media (DTR media) according to another embodiment of the present invention;

FIGS. 6A, 6B, 6C, 6D, 6E and 6F are cross-sectional views showing a method of manufacturing the HDD substrate shown in FIG. 4 and the DTR media shown in FIG. 5; and

FIG. 7 is a perspective view showing a magnetic recording apparatus according to an embodiment of the present invention.

DETAILED DESCRIPTION OF THE INVENTION

The substrate according to an embodiment of the present invention comprises circumferential protrusions and circumferential recesses formed on the surface. The protrusions correspond to the recording tracks and the recesses correspond to the grooves between the recording tracks. The surfaces of the recesses satisfy any of conditions (a) to (f) given below. If a granular magnetic layer is formed on the substrate for the magnetic recording media satisfying

any of these conditions, the magnetic orientation of the magnetic layer on the recess is made smaller than that of the magnetic layer on the protrusion, making it possible to prevent the signal-to-noise ratio (SNR) from being lowered by magnetic signals from the recesses. The conditions noted above, i.e., (a) to (f), will be described in more detail.

(a) The surface of the recess has a surface energy smaller than that of the surface of the protrusion. If the surface energy is small, the bonding force between the magnetic film and the substrate is weakened so as to disturb the crystal structure controlling the magnetic orientation of the magnetic film. In order to satisfy the particular condition, the surface of the recess is modified by a surface treating agent with a low surface energy containing, for example, a fluorine atom. The surface treating agent noted above includes, for example, fluoroalkylsilane (FAS) such as tetrahydrodecyltriethoxysilane, heptafluoro-1,1,2,2-tetrahydrodecyltrimethoxysilane, heptafluoro-1,1,2,2-tetrahydrodecyltrichlorosilane, tridecafluoro-1,1,2,2-tetrahydrooctyltriethoxysilane, tridecafluoro-1,1,2,2-tetrahydrooctyltrimethoxysilane, tridecafluoro-1,1,2,2-tetrahydrooctyltrichlorosilane and trifluoropropyltrimethoxysilane.

(b) The surface of the recess is modified with a thermally decomposable material or a thermally deformable material. The thermally decomposable material includes, for example, polyethylene glycol and poly (tetramethylene glycol). Also, the thermally deformable material includes, for example, a thermoplastic polymer such as polyvinyl alcohol and polyisobutyl methacrylate.

(c) The surface of the recess has surface roughness smaller than that of the surface of the protrusion. The particular condition can be achieved by the combination of the polishing and the etching.

(d) The crystal orientation is more disturbed on the surface of the recess, compared with the surface of the protrusion. The particular condition can be achieved by controlling the irradiation of a single crystal substrate such as a silicon substrate with an ion beam.

(e) The surface of the recess is modified with a substance that causes reaction with a magnetic material or that diffuses into the magnetic material. The reactive substance includes, for example, polyvinyl chloride having chlorine atoms. Also, the substance that diffuses into the magnetic material includes, for example, Cu.

(f) The surface of the recess is modified with a substance soluble in a solvent or a deformable

substance. The substance soluble in a solvent or deformable includes, for example, various polymers. It suffices to use an appropriate solvent in accordance with the kind of the polymer.

5 It should be noted that, in the substrate for the magnetic recording media according to the embodiment of the present invention, the difference in height between the protrusion and the recess preferably ranges between 10 and 100 nm.

10 In the general method of manufacturing the substrate for the magnetic recording media according to the embodiment of the present invention, the substrate is first coated with resist, followed by forming a resist pattern by imprinting or electron-
15 beam lithography and subsequently etching the substrate so as to obtain a substrate having protrusions and recesses. In this case, the resist is left unremoved on the protrusions. In the next step, deposited are, for example, a substance having a low
20 surface energy, a thermally decomposable substance, a thermally deformable substance, a reactive substance, and a substance soluble in a solvent, etc. It is possible to permit these substances to be left unremoved within the recess alone by peeling off the
25 resist on the protrusions (lift-off). In this case, it is necessary to allow these substances to be left unremoved when the resist is peeled off. To be more

specific, in the case of using an organic solvent for removing the resist, it is necessary to use a substance that is not peeled off by the organic solvent. In the case of using water for peeling off the resist, it is necessary to use a substance that is not peeled by water. Further, in the case of using an oxygen asher for peeling off the resist, it is necessary to use a substance capable of withstanding the oxygen asher. By such a simple method, it is possible to manufacture a desired substrate for the magnetic recording media, a magnetic recording media (DTR media) capable of suppressing degradation of the signal-to-noise ratio (SNR) caused by magnetic signals from the recesses, and a magnetic recording apparatus including the particular magnetic recording media.

EXAMPLES

[Example 1]

Used in this example is a surface modifying layer having a low surface energy. FIG. 1 is a cross-sectional view showing a substrate for a magnetic recording media (hereinafter referred to as an HDD substrate) according to an embodiment of the present invention. As shown in the drawing, circumferential protrusions corresponding to the recording tracks and circumferential recesses corresponding to the grooves between the recording tracks are formed on the surface of a glass substrate 11. A surface modifying layer 13

containing fluorine is formed on the surface of the recesses.

FIG. 2 is a cross-sectional view showing a magnetic recording media (DTR media) according to an embodiment of the present invention. As shown in the drawing, the surface modifying layer 13 is formed on the surface of the recesses of the glass substrate 11. Also, media films 14a and 14b are formed on the entire surface of the glass substrate 11. The media films include, for example, a soft underlayer, an orientation control film and a magnetic recording layer. The media film 14a denotes that formed on the protrusions (recording tracks). A magnetic recording layer satisfactory in its orientation is included in the regions of the media film 14a. Also, the media film 14b denotes that formed on the recesses (grooves). The orientation of the magnetic crystal lattice is disturbed in the region of the media film 14b.

The method of manufacturing the HDD substrate shown in FIG. 1 and the DTR media shown in FIG. 2 will be described with reference to FIGS. 3A, 3B, 3C, 3D, 3E and 3F. In the first step, a polymethyl methacrylate (PMMA) film 12 is formed in a thickness of 70 nm by spin-coating on the glass substrate 11 having a diameter of 0.85 inch as shown in FIG. 3A. On the other hand, prepared is a Ni mold 31 having

circumferential protrusions with a pitch of 100 nm, a top width of 35 nm and a height of 30 nm and also having protrusions corresponding to the address signals and servo signals. These protrusions are formed by electron-beam lithography and plating. The Ni mold 31 thus prepared is pressed to the PMMA film 12 so as to transfer the patterns of protrusions and recesses on the Ni mold 31 onto the PMMA film 12 as shown in FIG. 3B. After the Ni mold 31 is removed, the recesses of the PMMA film 12 are etched by Ar ion milling until the underlying glass substrate 11 is exposed. Further, the glass substrate 11 is selectively etched by RIE using a fluorine-based gas so as to transfer the patterns of protrusions and recesses on the Ni mold 31 to the glass substrate 11 as shown in FIG. 3C. In this stage, the PMMA film 12 is left unremoved on the protrusions. Then, the surface of the recess is treated with heptadecafluoro-1,1,2,2-tetrahydrodecyltrimethoxysilane, which is a surface treating agent containing fluorine atoms, so as to form the surface modifying layer 13 having a low surface energy as shown in FIG. 3D. Then, the PMMA film 12 is removed from the protrusions by a lift-off method using a solvent, thereby manufacturing the HDD substrate shown in FIG. 1. The HDD substrate thus manufactured is found to have circumferential protrusions with a pitch of 100 nm, a top width of

60 nm, and a height of 20 nm and to have patterns of protrusions and recesses corresponding to the address signals and servo signals, as shown in FIG. 3E.

5 The HDD substrate is loaded in a multi-chamber sputtering apparatus so as to form a soft underlayer, an orientation control film, a perpendicular magnetic recording layer of a granular structure formed of a mixture of CoCrPt and SiO₂, and a carbon protective film without breaking vacuum to manufacture the DTR
10 media shown in FIG. 2, as shown in FIG. 3F. A cross-section of the DTR media thus manufactured is observed with a TEM. The magnetic crystal lattice of the media film 14b on the recess (groove) is found to be disturbed, compared with the magnetic crystal lattice
15 of the media film 14a on the protrusion (recording track).

It is possible to coat the DTR media with a lubricant and to store the DTR media coated with the lubricant before assembly of the HDD. This is also
20 the case with the other Examples and Comparative Examples described in the following.

[Comparative Example 1]

An HDD substrate is manufactured as in Example 1, except that the treatment with a surface treating
25 agent containing fluorine atoms is not performed. Then, a DTR media is manufactured as in Example 1 using the HDD substrate noted above. A cross-section

of the DTR media thus manufactured is observed with a TEM, with the result that no change is recognized in the orientation of the magnetic crystal lattice between the recess and the protrusion.

5 [Example 2]

Used in this Example is a surface modifying layer formed of a thermally decomposable substance and soluble in a solvent. A polymethyl methacrylate (PMMA) film is formed in a thickness of 80 nm on a
10 glass substrate having a diameter of 1 inch by spin-coating. On the other hand, prepared is a Ni mold having circumferential protrusions with a pitch of 150 nm, a top width of 50 nm and a height of 50 nm and also having protrusions corresponding to the address
15 signals and servo signals. The Ni mold is prepared by electron-beam lithography and plating. The Ni mold is pressed to the PMMA film so as to transfer the patterns of protrusions and recesses onto the PMMA film. After the Ni mold is removed, the recess of the
20 PMMA film is etched by Ar ion milling until the surface of the underlying glass substrate is exposed. Further, the patterns of protrusions and recesses are transferred into the glass substrate by RIE using a fluorine-based gas. In this stage, the PMMA film on
25 the protrusion is left unremoved. In the next step, the substrate is coated by spin-coating with an aqueous solution of a thermally decomposable

polyethylene glycol, followed by removing the PMMA film by a lift-off method using an organic solvent, thereby manufacturing a desired HDD substrate. The HDD substrate is found to have circumferential protrusions with a pitch of 150 nm, a top width of 90 nm and a height of 40 nm and to have patterns of protrusions and recesses corresponding to the address signals and servo signals.

The HDD substrate is loaded in a multi-chamber sputtering apparatus so as to form a soft underlayer, an orientation control film, a granular perpendicular magnetic recording layer, and a carbon protective film without breaking vacuum, thereby manufacturing a DTR media. A cross-section of the DTR media thus manufactured is observed with a TEM, with the result that the orientation of the magnetic crystal lattice on the recess is found to be disturbed, compared with that of the magnetic crystal lattice on the protrusion.

[Comparative Example 2]

A HDD substrate is manufactured as in Example 2, except that a film of the decomposable substance is not formed and, then, a DTR media is manufactured as in Example 2. A cross-section of the DTR thus manufactured is observed with a TEM, with the result that no change is recognized in the orientation of the magnetic crystal lattice between the recess and the

protrusion.

[Example 3]

Used is a surface modifying layer formed of a thermally deformable substance and soluble in a solvent. Specifically, a polymethyl methacrylate (PMMA) film is formed in a thickness of 50 nm on a glass substrate having a diameter of 1.8 inches by spin-coating. On the other hand, prepared is a Ni mold having circumferential protrusions with a pitch of 150 nm, a top width of 50 nm and a height of 20 nm and also having protrusions corresponding to the address signals and servo signals. These protrusions are formed by electron-beam lithography and plating. The Ni mold is pressed to the PMMA film so as to transfer the patterns of protrusions and recesses of the Ni mold onto the PMMA film. After the Ni mold is removed, the recess of the PMMA film is etched by Ar ion milling until the surface of the underlying glass substrate is exposed. Further, the patterns of protrusions and recesses are transferred into the glass substrate by RIE using a fluorine-based gas. In this stage, the PMMA film on the protrusion is left unremoved. In the next step, the substrate is coated by spin-coating with an aqueous solution of a thermally deformable polyvinyl alcohol, followed by removing the PMMA film by a lift-off method using a solvent, thereby manufacturing a desired HDD

substrate. The HDD substrate is found to have
circumferential protrusions with a pitch of 150 nm, a
top width of 90 nm and a height of 10 nm and to have
patterns of protrusions and recesses corresponding to
5 the address signals and servo signals.

The HDD substrate is loaded in a multi-chamber
sputtering apparatus so as to form a soft underlayer,
an orientation control film, a granular perpendicular
magnetic recording layer, and a carbon protective film
10 without breaking vacuum, thereby manufacturing a DTR
media (Example 3A). A cross-section of the DTR media
thus manufactured is observed with a TEM, with the
result that the orientation of the magnetic crystal
lattice on the recess is found to be disturbed,
15 compared with that of the magnetic crystal lattice on
the protrusion.

Also, the HDD substrate is loaded in a multi-
chamber sputtering apparatus so as to form a soft
underlayer, an orientation control film, and a
20 granular perpendicular magnetic recording layer.
Then, the HDD substrate is washed with water, followed
by drying the substrate and, then, forming a carbon
protective film on the substrate, thereby
manufacturing a DTR media (Example 3B). A cross-
25 section of the DTR media thus manufactured is observed
with a TEM, with the result that the orientation of
the magnetic crystal lattice on the recess is found to

be disturbed, compared with that of the magnetic crystal lattice on the protrusion.

[Example 4]

Used is a surface modifying layer formed of a
5 thermally deformable substance and soluble in a
solvent. Specifically, a polyvinyl alcohol (PVA) film
is formed in a thickness of 120 nm on a glass
substrate having a diameter of 1.8 inches by spin-
coating. On the other hand, prepared is a Ni mold
10 having circumferential protrusions with a pitch of
150 nm, a top width of 40 nm and a height of 70 nm and
also having protrusions corresponding to the address
signals and servo signals. These protrusions are
formed by electron-beam lithography and plating. The
15 Ni mold is pressed to the PVA film so as to transfer
the patterns of protrusions and recesses of the Ni
mold onto the PVA film. After the Ni mold is removed,
the recess of the PVA film is etched by Ar ion milling
until the surface of the underlying glass substrate is
20 exposed. Further, the patterns of protrusions and
recesses are transferred into the glass substrate by
RIE using a fluorine-based gas. In this stage, the
PVA film on the protrusion is left unremoved. In the
next step, the substrate is coated by spin-coating
25 with a toluene solution of a thermally deformable
polyisobutyl methacrylate, followed by removing the
PVA film by a lift-off method using water, thereby

manufacturing a desired HDD substrate. The HDD
substrate is found to have circumferential protrusions
with a pitch of 150 nm, a top width of 95 nm and a
height of 60 nm and to have patterns of protrusions
5 and recesses corresponding to the address signals and
servo signals.

The HDD substrate is loaded in a multi-chamber
sputtering apparatus so as to form a soft underlayer,
an orientation control film, a granular perpendicular
10 magnetic recording layer, and a carbon protective film
without breaking vacuum, thereby manufacturing a DTR
media (Example 4A). A cross-section of the DTR media
thus manufactured is observed with a TEM, with the
result that the orientation of the magnetic crystal
15 lattice on the recess is found to be disturbed,
compared with that of the magnetic crystal lattice on
the protrusion.

Also, the HDD substrate is loaded in a multi-
chamber sputtering apparatus so as to form a soft
20 underlayer, an orientation control film, and a
granular perpendicular magnetic recording layer.
Then, the HDD substrate is washed with toluene,
followed by drying the substrate and, then, forming a
carbon protective film on the substrate, thereby
25 manufacturing a DTR media (Example 4B). A cross-
section of the DTR media thus manufactured is observed
with a TEM, with the result that the orientation of

the magnetic crystal lattice on the recess is found to be disturbed, compared with that of the magnetic crystal lattice on the protrusion.

[Example 5]

5 Used is a surface modifying layer formed of a thermally decomposable substance and soluble in a solvent. Specifically, a polyvinyl alcohol (PVA) film is formed in a thickness of 90 nm on a glass substrate having a diameter of 1.8 inches by spin-coating. On
10 the other hand, prepared is a Ni mold having circumferential protrusions with a pitch of 100 nm, a top width of 35 nm and a height of 40 nm and also having protrusions corresponding to the address signals and servo signals. These protrusions are
15 formed by electron-beam lithography and plating. The Ni mold is pressed to the PVA film so as to transfer the patterns of protrusions and recesses of the Ni mold onto the PVA film. After the Ni mold is removed, the recess of the PVA film is etched by Ar ion milling
20 until the surface of the underlying glass substrate is exposed. Further, the patterns of protrusions and recesses are transferred into the glass substrate by RIE using a fluorine-based gas. In this stage, the PVA film on the protrusion is left unremoved. In the
25 next step, the substrate is coated by spin-coating with an ethyl acetate solution of a thermally deformable poly (tetramethylene glycol), followed by

removing the PVA film by a lift-off method using water, thereby manufacturing a desired HDD substrate. The HDD substrate is found to have circumferential protrusions with a pitch of 100 nm, a top width of 55 nm and a height of 25 nm and to have patterns of protrusions and recesses corresponding to the address signals and servo signals.

The HDD substrate is loaded in a multi-chamber sputtering apparatus so as to form a soft underlayer, an orientation control film, a granular perpendicular magnetic recording layer, and a carbon protective film without breaking vacuum, thereby manufacturing a DTR media (Example 5A). A cross-section of the DTR media thus manufactured is observed with a TEM, with the result that the orientation of the magnetic crystal lattice on the recess is found to be disturbed, compared with that of the magnetic crystal lattice on the protrusion.

Also, the HDD substrate is loaded in a multi-chamber sputtering apparatus so as to form a soft underlayer, an orientation control film, and a granular perpendicular magnetic recording layer. Then, the HDD substrate is washed with ethyl acetate, followed by drying the substrate and, then, forming a carbon protective film on the substrate, thereby manufacturing a DTR media (Example 5B). A cross-section of the DTR media thus manufactured is observed

with a TEM, with the result that the orientation of the magnetic crystal lattice on the recess is found to be disturbed, compared with that of the magnetic crystal lattice on the protrusion.

5 [Example 6]

 In this Example, the surface roughness on the surface of the recess is made smaller than that on the surface of the projection. Specifically, a glass substrate having a diameter of 1.8 inches is polished
10 with fine particles so as to form roughness with Ra of 2 nm. Then, a polystyrene (PSt) film is formed on the glass substrate in a thickness of 100 nm by spin-coating. On the other hand, prepared is a Ni mold having circumferential protrusions with a pitch of
15 150 nm, a width of 50 nm and a height of 60 nm and also having protrusions corresponding to the address signals and servo signals. These protrusions are formed by electron-beam lithography and plating. The Ni mold is pressed to the PSt film so as to transfer
20 the patterns of protrusions and recesses onto the PSt film. After the Ni mold is removed, the recess of the PSt film is etched by Ar ion milling until the surface of the underlying glass substrate is exposed.
Further, the patterns of protrusions and recesses are
25 transferred into the glass substrate by RIE using a fluorine-based gas. As a result, the roughness Ra on the surface of the recess of the glass substrate is

lowered to 0.5 nm. In the next step, the PSt layer is removed with an oxygen asher so as to obtain a desired HDD substrate. The HDD substrate is found to include circumferential protrusions with a pitch of 150 nm, a
5 top width of 90 nm and a height of 45 nm and is also found to include an irregularity corresponding to the address signals and servo signals.

The HDD substrate is loaded in a multi-chamber sputtering apparatus so as to form a soft underlayer,
10 an orientation control film, a granular perpendicular magnetic recording layer and a carbon protective film without breaking vacuum, thereby manufacturing a DTR media. A cross-section of the DTR media thus manufactured is observed with a TEM, with the result
15 that the orientation of the magnetic crystal lattice on the recess is found to be disturbed, compared with that of the magnetic crystal lattice on the protrusion.

[Example 7]

20 In this Example, the crystal orientation on the surface of the recess is disturbed, compared with that on the surface of the protrusion. Specifically, a polymethyl methacrylate (PMMA) film is formed in a thickness of 80 nm on a Si disc substrate having a
25 diameter of 1 inch by spin-coating. On the other hand, prepared is a Ni mold having circumferential protrusions with a pitch of 100 nm, a top width of

35 nm and a height of 30 nm and also having protrusions corresponding to the address signals and servo signals. These protrusions are formed by electron-beam lithography and plating. The Ni mold is pressed to the PMMA film so as to transfer the patterns of protrusions and recesses of the Ni mold onto the PMMA film. After the Ni mold is removed, the recess of the PMMA film is etched by means of the Ar ion milling so as to expose selectively the surface of Si disc substrate, followed by transferring the patterns of protrusions and recesses into the Si disc substrate. In this stage, the PMMA film on the protrusion is left unremoved. In the next step, the PMMA film is removed by using an organic solvent, thereby manufacturing a desired HDD substrate. A cross-section of the HDD substrate is observed with TEM, with the result that the crystal orientation on the surface of the Si crystal on the recess is found to have been disturbed by the irradiation with the Ar ions, compared with the crystal orientation on the surface of the Si crystal on the protrusion. The HDD substrate is found to have circumferential protrusions with a pitch of 100 nm, a top width of 60 nm and a height of 15 nm and to have patterns of protrusions and recesses corresponding to the address signals and servo signals.

The HDD substrate is loaded in a multi-chamber

sputtering apparatus so as to form a soft underlayer,
an orientation control film, a granular perpendicular
magnetic recording layer, and a carbon protective film
without breaking vacuum, thereby manufacturing a DTR
5 media. A cross-section of the DTR media thus
manufactured is observed with a TEM, with the result
that the orientation of the magnetic crystal lattice
on the recess is found to be disturbed, compared with
that of the magnetic crystal lattice on the
10 protrusion.

[Example 8]

In this Example, used on the surface of the
recess is a surface modifying layer formed of a
substance capable of reacting with a magnetic material
15 and soluble in a solvent. Specifically, a polyvinyl
alcohol (PVA) film is formed in a thickness of 100 nm
on a Si/SiO₂ substrate having a diameter of 1.8 inches
by spin-coating. On the other hand, prepared is a Ni
mold having circumferential protrusions with a pitch
20 of 150 nm, a top width of 50 nm and a height of 15 nm
and also having protrusions corresponding to the
address signals and servo signals. These protrusions
are formed by electron-beam lithography and plating.
The Ni mold is pressed to the PVA film so as to
25 transfer the patterns of protrusions and recesses of
the Ni mold onto the PVA film. After the Ni mold is
removed, the recess of the PVA film is etched by Ar

ion milling until the surface of the underlying glass substrate is exposed. Further, the patterns of protrusions and recesses are transferred into the glass substrate by RIE using a fluorine-based gas. In this stage, the PVA film on the protrusion is left unremoved. In the next step, the substrate is coated by spin-coating with a toluene solution of polyvinyl chloride having chlorine atoms that perform a reaction with the magnetic material, followed by removing the PVA film by a lift-off method using water, thereby manufacturing a desired HDD substrate. The HDD substrate is found to have circumferential protrusions with a pitch of 150 nm, a top width of 95 nm and a height of 10 nm and to have patterns of protrusions and recesses corresponding to the address signals and servo signals.

The HDD substrate is loaded in a multi-chamber sputtering apparatus so as to form a soft underlayer, an orientation control film, a granular perpendicular magnetic recording layer, and a carbon protective film without breaking vacuum, thereby manufacturing a DTR media. A cross-section of the DTR media thus manufactured is observed with a TEM, with the result that the orientation of the magnetic crystal lattice on the recess is found to be disturbed, compared with that of the magnetic crystal lattice on the protrusion.

[Example 9]

In this Example, a surface modifying layer formed on the surface of the recess is formed of a substance that can diffuse into a magnetic material.

5 Specifically, a polyvinyl alcohol (PVA) film is formed in a thickness of 100 nm on a glass substrate having a diameter of 1.8 inches by spin-coating. On the other hand, prepared is a Ni mold having circumferential protrusions with a pitch of 150 nm, a top width of
10 50 nm and a height of 50 nm and also having protrusions corresponding to the address signals and servo signals. These protrusions are formed by electron-beam lithography and plating. The Ni mold is pressed to the PVA film so as to transfer the patterns
15 of protrusions and recesses of the Ni mold onto the PVA film. After the Ni mold is removed, the recess of the PVA film is etched by Ar ion milling until the surface of the underlying glass substrate is exposed. Further, the patterns of protrusions and recesses are
20 transferred into the glass substrate by RIE using a fluorine-based gas. In this stage, the PVA film on the protrusion is left unremoved. In the next step, a film of Cu that can diffuse into the magnetic material is formed by sputtering, followed by removing the PVA
25 film by means of lift-off with water, thereby manufacturing a desired HDD substrate. The HDD substrate is found to have circumferential protrusions

with a pitch of 150 nm, a top width of 90 nm and a height of 40 nm and to have patterns of protrusions and recesses corresponding to the address signals and servo signals.

5 The HDD substrate is loaded in a multi-chamber sputtering apparatus so as to form a soft underlayer, an orientation control film, a magnetic recording layer, and a carbon protective film without breaking vacuum, thereby manufacturing a DTR media. A cross-
10 section of the DTR media thus manufactured is observed with a TEM, with the result that the orientation of the magnetic crystal lattice on the recess is found to be disturbed, compared with that of the magnetic crystal lattice on the protrusion.

15 [Example 10]

 FIG. 4 is a cross-sectional view showing an HDD substrate according to another embodiment of the present invention. As shown in the drawing, a soft underlayer 22 is formed on a glass substrate 21, and
20 an orientation control film 23 made of Pd is formed on the soft underlayer 22. Circumferential protrusions corresponding to the recording tracks are formed by the orientation control film 23. The regions free from the orientation control film 23 form pattern of
25 circumferential recesses corresponding to the grooves between the recording tracks.

 FIG. 5 is a cross-sectional view showing a

magnetic recording media (DTR media) according to an embodiment of the present invention. As shown in the drawing, the soft underlayer 22 is formed on the glass substrate 21, and the orientation control film 23 made of Pd is formed on the soft underlayer 22 in a manner to form protrusions. Further, perpendicular magnetic recording layers 25a, 25b are formed on the entire surface. The reference numeral 25a denotes a perpendicular magnetic recording layer formed on the orientation control film 23 on the protrusions (recording tracks). In the regions, the magnetic orientation is good. Also, the reference numeral 25b denotes a perpendicular magnetic recording layer formed on the recesses (grooves). In the regions, the magnetic orientation is disturbed.

The manufacturing method of the HDD substrate shown in FIG. 4 and the DTR media shown in FIG. 5 will be described with reference to FIGS. 6A, 6B, 6C, 6D, 6E and 6F. In the first step, a glass substrate 21 having a diameter of 0.85 inch is loaded in a multi-chamber sputtering apparatus so as to form a soft underlayer 22 and an orientation control film 23 made of Pd, as shown in FIG. 6A. In the next step, a polymethyl methacrylate (PMMA) film 24 is formed on the orientation control film 23 by spin-coating in a thickness of 80 nm, as shown in FIG. 6B. On the other hand, prepared is a Ni mold 31 having circumferential

protrusions with a pitch of 100 nm, a top width of 35 nm and a height of 30 nm also having protrusions corresponding to the address signals and servo signals. These protrusions are formed by electron-beam lithography and plating. The Ni mold 31 is pressed to the PMMA film 24 so as to transfer the patterns of protrusions and recesses of the Ni mold 31 onto the PMMA film 24, as shown in FIG. 6C. After the Ni mold 31 is removed, patterns of protrusions and recesses are formed on the orientation control film 23 by Ar ion milling. At this stage, the PMMA 24 film is left unremoved on the protrusion. In the next step, the PMMA film is removed by using an organic solvent so as to form the HDD substrate shown in FIG. 4 as shown in FIG. 6E. The HDD substrate thus formed included circumferential protrusions with a pitch of 100 nm, a top width of 55 nm and a height of 15 nm and also included patterns of protrusions and recesses corresponding to the address signals and servo signals.

The HDD substrate is loaded in a multi-chamber sputtering apparatus so as to form a perpendicular magnetic recording layer of a granular structure, and a carbon protective film without breaking vacuum so as to obtain a DTR media as shown in FIG. 6F. A cross-section of the DTR media thus obtained is observed with a TEM, with the result that the orientation of

the perpendicular magnetic crystals in the
perpendicular magnetic recording layer 25b on the
recess is found to be disturbed, compared with that of
the perpendicular magnetic crystals in the
5 perpendicular magnetic recording layer 25a on the
protrusion.

FIG. 7 is a perspective view showing a magnetic
recording apparatus according to an embodiment of the
present invention. As shown in the drawing, the
10 magnetic recording apparatus comprises a chassis 50.
Arranged within the chassis 50 are a magnetic
recording media (DTR media) 10, a spindle motor 51 for
rotating the DTR media 10, a head slider 55, a head
suspension assembly for supporting the head slider 55
15 (i.e., combination of a suspension 54 and an actuator
arm 53), a voice coil motor (VCM) 56 and a circuit
board. The DTR media 10 is mounted to the spindle
motor 51 so as to be rotated by the spindle motor 51,
with the result that various digital data are recorded
20 in the DTR media 10. The magnetic head incorporated
in the head slider 55 is a so-called integrated type
including a single pole head and a GMR element. The
suspension 54 is held at one end of the actuator arm
53, and the head slider 55 is supported by the
25 suspension 54 in a manner to face the recording
surface of the DTR media 10. The actuator arm 53 is
mounted to a pivot 52. The voice coil motor (VCM) 56

is mounted as an actuator at the other end of the actuator arm 53. The head suspension assembly is actuated by the voice coil motor (VCM) 56 so as to permit the magnetic head to be positioned over
5 arbitrary radial position of the DTR media 10. The circuit board comprises a head IC so as to generate driving signals for the voice coil motor (VCM) and control signals for controlling read/write performed by the magnetic head.

10 The DTR media manufactured in each of the Examples and the Comparative Examples described above is coated with a lubricant having a fluorinated alkyl group so as to manufacture the magnetic recording apparatus shown in FIG. 7. In the DTR media having
15 circumferential protrusions with a pitch of 100 nm, the width of the read magnetic sensor is set at 55 nm and the width of the single pole head is set at 70 nm. In the DTR media having circumferential protrusions formed at a pitch of 150 nm, the width of the read
20 magnetic sensor is set at 80 nm and the width of the single pole head is set at 100 nm. The DTR media is rotated at a rotating speed of 5,000 rpm and read/write is performed using a head slider with a flying height of 10 nm. Table 1 shows the SNR of the
25 output signals.

In Example 1, the SNR is found to be 15 dB, whereas the SNR for Comparative Example 1 is found to

be only 12 dB. Similarly, the SNR for Example 2 is found to be 18 dB, whereas the SNR for Comparative Example 2 is found to be only 14 dB. The experimental data support that the SNR is lowered by the magnetic signals from the recesses in the Comparative Examples. However, it is possible to overcome the difficulty in the Examples of the present invention.

Table 1

	SNR (dB)
Example 1	15
Comparative Example 1	12
Example 2	18
Comparative Example 2	14
Example 3A	17
Example 3B	18
Example 4A	18
Example 4B	18.5
Example 5A	15
Example 5B	15.5
Example 6	19
Example 7	14.5
Example 8	14.5
Example 9	16
Example 10	15.5

WHAT IS CLAIMED IS:

1. A substrate for a magnetic recording media,
comprising:

circumferential protrusions corresponding to
5 recording tracks and circumferential recesses
corresponding to grooves between the recording tracks;
the substrate satisfying at least one of
conditions (a) to (f) given below:

(a) a surface of the recess has a surface energy
10 smaller than that of a surface of the protrusion;

(b) the surface of the recess is modified with a
thermally decomposable or thermally deformable
substance;

(c) the surface of the recess has surface
15 roughness smaller than that of the surface of the
protrusion;

(d) crystal orientation is more disturbed on the
surface of the recess than on the surface of the
protrusion;

20 (e) the surface of the recess is modified with a
substance that causes reaction with a magnetic
material or that diffuses into the magnetic material;
and

(f) the surface of the recess is modified with a
25 substance soluble in a solvent or with a deformable
substance.

2. The substrate according to claim 1, wherein

the surface of the recess is modified with a substance containing fluorine.

3. The substrate according to claim 2, wherein the substance containing fluorine is
5 fluoroalkylsilane.

4. The substrate according to claim 1, wherein the thermally decomposable material is selected from the group consisting of polyethylene glycol and poly (tetramethylene glycol).

10 5. The substrate according to claim 1, wherein the thermally deformable material is selected from the group consisting of polyvinyl alcohol and polyisobutyl methacrylate.

6. The substrate according to claim 1, wherein
15 the substance that causes reaction with a magnetic material is polyvinyl chloride.

7. The substrate according to claim 1, wherein the substance that diffuses into the magnetic material is Cu.

20 8. The substrate according to claim 1, wherein the difference in height between the protrusion and the recess ranges between 10 and 100 nm.

9. The substrate according to claim 1, wherein the substrate is formed of glass or silicon.

25 10. A magnetic recording media, comprising:
the substrate for a magnetic recording media according to claim 1; and

a granular magnetic layer formed on the substrate
for the magnetic recording media,

the orientation of the magnetic crystal lattice
of the magnetic layer on the recess being more
5 disturbed than that of the magnetic layer on the
protrusion.

11. A magnetic recording apparatus, comprising:
the magnetic recording media according to claim 10;
and a magnetic head.